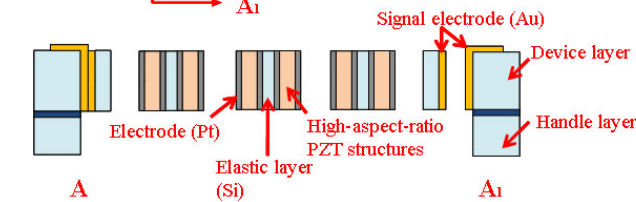
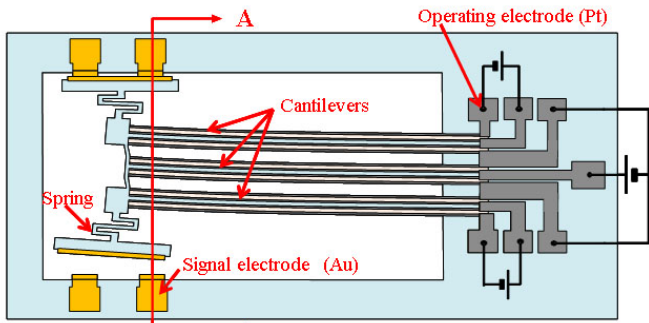
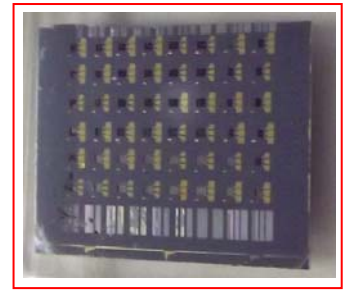
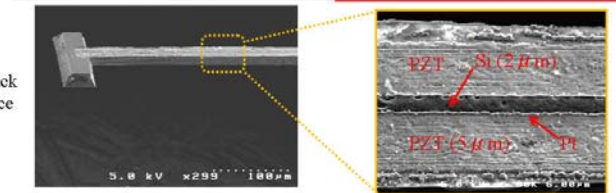
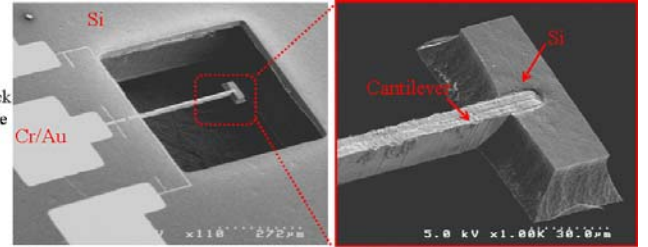


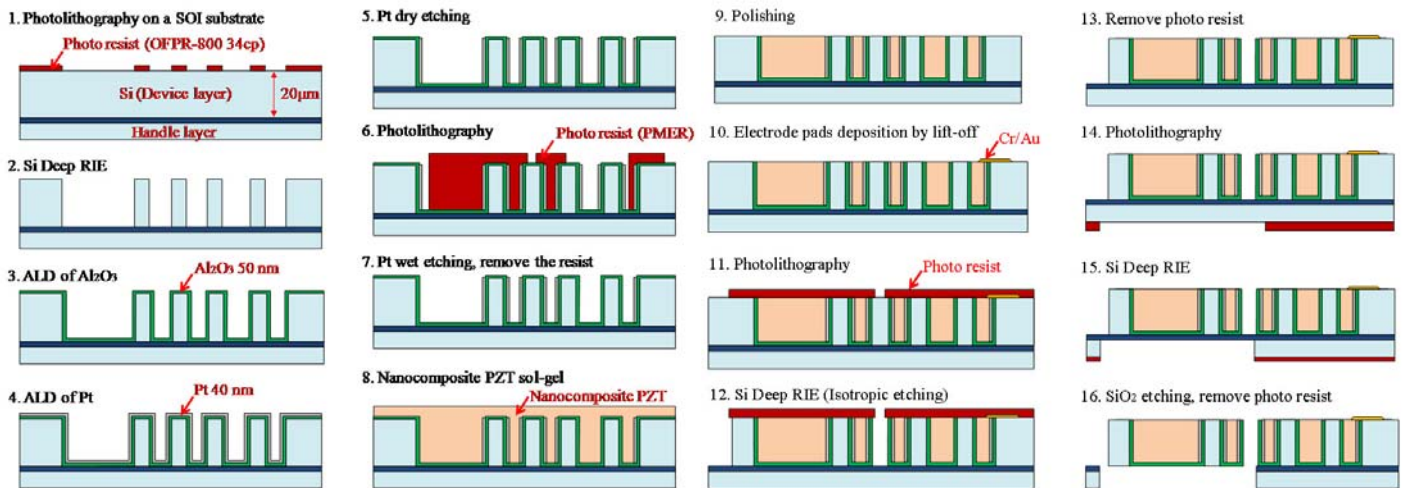
横方向駆動圧電マイクロアクチュエータ



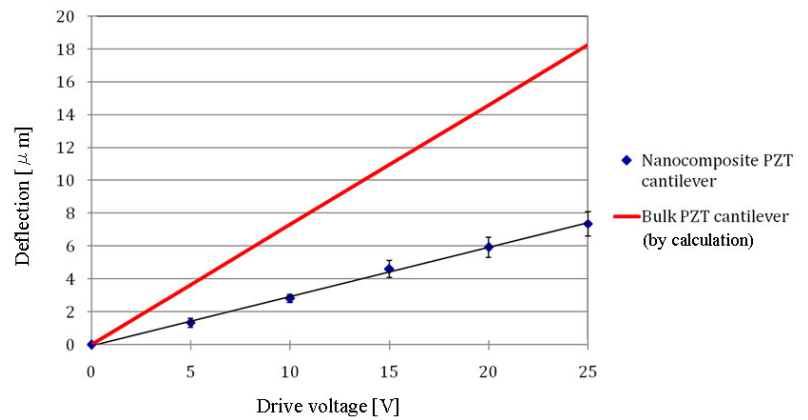
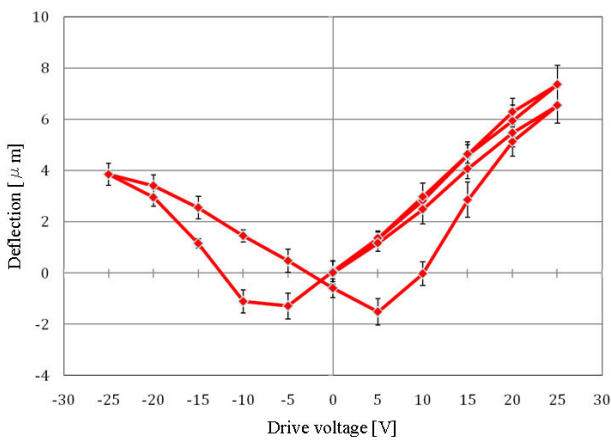
構造



写真



製作工程



駆動電圧と変位

横方向駆動圧電マイクロアクチュエータ

参考文献 : N.Wang, S.Yoshida, M.Kumano, Y.Kawai and M.Esashi, Fabrication of High-aspect-ratio PZT Structure by Nanocomposite SOI-gel Method for Laterally-driven Piezoelectric MEMS Switch, 2012 7th IEEE Intl. Conf. on Nano/Micro Engineered and Molecular Systems (IEEE NEMS 2012) (2012) pp.321-326